Docket No.

209291US0

IN RE APPLICATION OF: Hiroyuki NAGASAWA, et al.

SERIAL NO: 09 867,467

FILED: FOR:

May 31, 2001 METHOD OF MANUFACTURING SILICON CARBIDE, SILICON CARBIDE, COMPOSITE MATERIAL,

AND SEMICONDUCTOR ELEMENT

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

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SIR:

Transmitted herewith is an amendment w/attached marked-up copy in the above-identified application.

☐ No additional fee is required

☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.

■ Additional documents filed herewith: Letter Requesting Approval of Drawing Changes; Figure 7 (w/corrections in red)

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS		RATE		CALCULATIONS
TOTAL	16	MINUS	20	0	x	\$18	=	\$0.00
INDEPENDENT	3	MINUS	3	0	x	\$84	=	\$0.00
	☐ MULTIPLE DEPENDENT CLAIMS + \$280 =					=	\$0.00	
TOTAL OF ABOVE CALCULATION Reduction by 50% for filing by Small Entity				ONS	\$0.00			
					\$0.00			
		☐ Recordation of Assignment + \$40 =				=	\$0.00	
						TOT	AL	\$0.00

	Α	chec	k in	the	amount	of	\$0.00	_1S	attacl	hed	I.
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- Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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DOCKET NO.: 209291US0

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

:

Hiroyuki NAGASAWA et al

: GROUP: 1765

SERIAL NO.: 09/867,467

: EXAMINER: M. Song

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10 3700

FILED: May 31, 2001

FOR: METHOD OF MANUFACTURING SILICON CARBIDE,

SILICON CARBIDE COMPOSITE MATERIAL,

AND SEMICONDUCTOR ELEMENT

LETTER REQUESTING APPROVAL OF DRAWING CHANGES

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Please review for approval the proposed changes to the Formal Drawings shown in RED on the attached photocopies of the drawings. Once these changes have been reviewed and approved by the Examiner in charge of this case, instructions for their implementation will be forwarded to an approved bonded draftsman.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Norman F. Oblon

Attorney of Record

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